

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S20	11	US-6555403-\$.DID. OR US-6720586-\$. DID. OR US-6872982- \$.DID. OR US- 7067846-\$.DID. OR US-20060261352-\$. DID.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:26
S21	2	EP-1014520-\$.DID.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:37
S22	0	S20 and metal adj (layer film material) and active adj (layer film material)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:41
S23	1634	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:42
S24	117	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:43
S25	32	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:43

S26	26	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and @ay<="2003"	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 02:44
S27	2	EP-1014520-\$.DID.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 03:16
S28	4	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and @ay<="2003" and crack\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 03:24

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